Overview

The Entegris A200 200 mm SMIF pod offers improved production yields through design and manufacturing experience and incorporation of features from an install base of over 200,000 unit pods. It is designed to provide contamination control to semiconductor manufacturers by protecting wafers during transport and storage in the manufacturing environment. The pod is an environmentally-secure wafer container that maintains a mini-environment for the wafers with inherent automation compatibility.

Features

- All pod components are constructed from materials chosen specifically for their low-particulate generation, low-organic outgassing and long life
- The standard pod shell is made of clear polycarbonate that is tough and durable, designed to withstand repeated manual and automatic handling
- The pod door is made of static dissipative polycarbonate to significantly reduce the likelihood of ESD damage
- The cassette hold down is compatible with automated pod cleaning systems, reducing the cost of ownership
- Wafer isolation is enhanced by the use of a high-performance gasket comprised of a proprietary formulation of a low-outgassing elastomer

Attributes

- Tough, durable polycarbonate shell and door
- Polycarbonate waferlock and waferlock frame
- Injection-molded PTFE-filled cassette hold down
- Carbon-filled polycarbonate door
- Injection-molded polycarbonate cassette guides
- Compatible with a wide variety of cassettes

Specifications

- Base dimensions: 283 mm × 292 mm (11.125” × 11.5”)
- Pod height (without top handle): 254 mm (10.0”)
- Weight (empty pod): 2.59 kg (5.7 lbs)
- Weight (pod shell): 1.62 kg (3.6 lbs)
- Weight (pod door): 0.87 kg (1.9 lbs)

Note: Conforms to SEMI® E19.4
Features and Benefits

<table>
<thead>
<tr>
<th>Features</th>
<th>Benefits</th>
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<tbody>
<tr>
<td>Polycarbonate shell with double wall base</td>
<td>Ensures secure seal between door and shell</td>
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<td></td>
<td>Promotes a clean wafer environment</td>
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<tr>
<td>Door design</td>
<td>Carbon-filled conductive door significantly reduces likelihood of ESD damage by providing direct path to ground</td>
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<td>Door latching mechanism evenly distributes force around perimeter of door, ensuring seal between door and shell</td>
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<td>Proprietary elastomeric door seal gasket ensures extremely low outgassing</td>
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<td>Waferlock mechanism</td>
<td>Waferlock engages wafers with no relative motion, eliminating tribogeneration of static charges and particles</td>
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<td>Polycarbonate waferlock ensures low outgassing</td>
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<tr>
<td>Overall pod</td>
<td>Minimization of internal metal parts limits susceptibility to corrosion and particulation</td>
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Options

**Shell Color Options:**
- Amber, green and clear shell

**Identification Options:**
- Bar code and alphanumeric character labels
- Color handles
- Lasermarking bar code and alphanumeric character
- Cardholder and traveler tag

**Handling Options:**
Top automation handle and carrying handle

For More Information

Please call your Regional Customer Service Center today to learn what Entegris can do for you. Visit www.entegris.com and select the Customer Service link for the center nearest you.

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